

RIKEN Symposium : 12nd SAP (Super Analyzer Platform) Symposium
「Research and Development of Analyzer Key Components for
Core Manufacturing Technology」

Date: 13:00-17:00, August 2, 2019

Venue: Kyushu University, Ito Campus, West zone 4, 9F

Using unique processing technologies developed in RIKEN, our research group promotes an establishment of fabrication technologies for creating critical Components (CC) and infrastructure technology development. Being motivated on developing the nano-precision machining process technologies which are continuously being upgraded through intensive R&D activities, primarily focusing on functional device fabrication for Super Analyzers, we intend to integrate a series of essential and hybrid process technologies into creating technologies for CC. By using these integrated technologies, we aim to develop functional elements such as optical ones, substrates and devices for sensing, and to create next-generation CC.

We organized the 12nd SAP Symposium to promote exchange of information in the fields of ELID technique, ultraprecise cutting for space telescope, advanced ELID grinding wheel, coating technology for photovoltaic cell and excellent polishing technology for MRF and CMP, and to strengthen relationship between our research group and the speakers in the variety fields of Super Analyzer development and applications.

Program;

Time	Title
Chair: Assoc. Prof. O.Ohnishi, Univ. of Miyazaki	
13:00-13:20	“Grinding Characteristics of Sapphire Using ELID and High Hardness Iron Plated Grinding Wheel” Masaki Ishitsuka, Ibaraki University
13:20-13:40	“Effect of ELID grinding on the Surface of Titanium Materials for Bio-Cell Activity Experiment” Tae-Soo Kwak, Gyeongnam Nat. Univ. of Sci. and Tech.
13:40-14:00	“Fabrication of Fresnel Lenses for Space Telescope by Diamond Turning in Combination with Final Polishing” Hiroshi Kasuga, RIKEN
14:00-14:20	Coffee Break
Chair: Dr. H.Kasuga, RIKEN	
14:20-14:40	“Fabrication and Characterization of Organic Thin Film Photovoltaic (OPV) Cell for Spray Coating” Yoshiyuki Seike, Aichi Institute of Technology
14:40-15:00	“Study on Damage Generation Mechanism and Process of Planar Magnetorheological Finishing Using Large Polishing Tool” Shaohui Yin, Hunan University
15:00-15:20	“Finishing Properties of X-ray Mirror by ELID-CMP Combined Process” Hitoshi Ohmori, RIKEN, Syuhei Kurokawa, Kyushu University
15:20-15:40	Coffee Break
15:40-17:00	Technical tour

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This Symposium is a part of the RIKEN Symposium Series.